On page 22, after line 2, please insert the following paragraph:

--The specification incorporates by reference the disclosure of German priority document 198 59 466.6 of 22 December 1998 and International priority document PCT/EP99/08862 of 18 May 1999.

The present invention is, of course, in no way restricted to the specific disclosure of the specification and drawings, but also encompasses any modifications within the scope of the appended claims.--

IN THE CLAIMS:

Please cancel claims 1 - 32, and replace them with the attached claims 33 - 62.

REMARKS

Claims 33 - 62 are pending in the application.

Appropriate headings have been added to the specification and the claims from the literal translation have been replaced by claims drafted in conformity with U.S. Patent practice.

The application in its amended state is believed to be in condition for allowance. However, should the Examiner have any comments or suggestions, or wish to discuss the merits of the application, the undersigned would very much welcome a telephone call in order to be able to expedite placement of the application into condition for allowance.

Respectfully submitted,

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WHAT WE CLAIM IS:

33. An apparatus for processing substrates, comprising:

a nozzle plate;

at least one first nozzle disposed essentially centrally relative to said nozzle plate and extending perpendicular thereto, wherein said at least one first nozzle provides a radial flow therefrom; and

a plurality of second nozzles disposed in said nozzle plate at an angle of less than 90° relative thereto, wherein said second nozzles are separately controllable from said at least one first nozzle, wherein said second nozzles provide a flow therefrom directed transverse to said radial flow from said at least one first nozzle, and wherein said second nozzles are distributed over said nozzle plates such that said transverse flow therefrom deflects said radial flow from said at least one first nozzle into a spirally outwardly extending flow.

34. An apparatus according to claim 33, wherein said at least one first nozzle is a single point nozzle.

35. An apparatus according to claim 33, wherein said second nozzles form at least one nozzle group, which extends along a prescribed contour, especially a straight line.

36. An apparatus according to claim 35, wherein said straight line extends tangential to said at least one first nozzle.

37. An apparatus according to claim 33, which includes at least one further nozzle, which is disposed between said at least one first nozzle and said second nozzles, and is directed radially relative to said at least one first nozzle.

38. An apparatus according to claim 33, wherein said second nozzles are

disposed in said nozzle plate at an angle of 45°.

39. An apparatus according to claim 33, wherein said second nozzles are point nozzles.

40. An apparatus according to claim 33, wherein said at least one first nozzle and said second nozzles can have different pressures and/or can be supplied with different fluids.

41. An apparatus according to claim 33, wherein a rinsing fluid can be conducted via said at least one first nozzle.

42. An apparatus according to claim 33, wherein a vacuum can be applied to said at least one first nozzle.

43. An apparatus according to claim 33, wherein a gas can be conducted via said second nozzles.

44. An apparatus according to claim 37, wherein a common base is provided for said at least one first nozzle, said second nozzles, and said at least one further nozzle.

45. An apparatus according to claim 44, wherein an insert is insertable into said base, and wherein said at least one first nozzle is provided in said insert.

46. An apparatus according to claim 33, wherein an annular fluid chamber is disposed beneath said nozzle plate.

47. An apparatus according to claim 44, wherein said base is provided with a surface that surrounds said nozzle plate and is disposed lower than said nozzle plate, wherein said surface is provided with a plurality of bores for accommodating a corresponding number of spacers.

48. An apparatus according to claim 47, wherein said spacers are